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## AMENDMENTS TO THE CLAIMS

- 1. (Currently Amended) An optical system comprising
- a light source for emission of a first light beam
- a first beamsplitter having a dielectric coating, the first beamsplitter being adapted to transmit/reflect transmitting/reflecting a secondary output light beam in response to said first light beam being incident upon said beamsplitter, and further being adapted to transmit/reflect transmitting/reflecting a primary output light beam in response to said first light beam being incident upon said beamsplitter, the power of the secondary output light beam being a substantially fixed percentage of the power of the primary output light beam,
- a detector being adapted to measure measuring the power of the secondary output light beam, and providing on the basis of the measured power a control signal to the light source, so that parameters of the first light source are adjusted in such a way that the output power of the primary output light beam is kept substantially constant.
- 2. (Original) A system according to claim 1, wherein the substantially fixed percentage of the secondary output light beam is substantially invariant to wavelength variations of the first light beam within a predetermined wavelength range.



3. (Original) A system according to claim 1, wherein the transmittance and/or reflection spectra of the dielectric coating of the beamsplitter is/are substantially invariant to wavelength changes of the first light beam in a predetermined wavelength range.



- 4. (Original) A system according to claim 2, wherein the predetermined wavelength range is between approximately 780 nm and approximately 830 nm.
- 5. (Original) A system according to claim 2, wherein the predetermined wavelength range is between approximately 620 nm and approximately 650 nm.
- 6. (Original) A system according to claim 2, wherein the predetermined wavelength range is between approximately 910 nm and approximately 1100 nm.
- 7. (Original) A system according to claim 2, wherein the predetermined wavelength range is between approximately 1450 nm and approximately 1550 nm.

- 8. (Original) A system according to claim 2, wherein the predetermined wavelength range is between approximately 1600 nm and approximately 1900 nm.
- 9. (Original) A system according to claim 2, wherein the predetermined wavelength range is between approximately 520 nm and approximately 585 nm.
- 10. (Original) A system according to claim 1, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, induces a variation in the power of the transmitted/reflected secondary light beam being within +/10 % of the power of the transmitted/reflected secondary light beam at a given wavelength within the predetermined wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/-10% of the substantially fixed percentage at the given wavelength.
- 11. (Original) A system according to claim 1, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, induces a variation in the power of the transmitted/reflected secondary light beam being within +/10 % of the average power of the transmitted/reflected secondary



light beam in the given wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/-10% of the average power of the transmitted/reflected secondary output light beam in the predetermined wavelength range.

- 12. (Original) A system according to claim 1, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, induces a variation in the power of the transmitted/reflected secondary light beam being within +/- 5 % of the power of the transmitted/reflected secondary light beam at a given wavelength within the predetermined wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/- 5 % of the substantially fixed percentage at the given wavelength.
- 13. (Original) A system according to claim 1, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, induces a variation in the power of the transmitted/reflected secondary light beam being within +/- 5 % of the average power of the transmitted/reflected secondary light beam in the given wavelength range so as to provide a variation in the substantially fixed percentage of the primary



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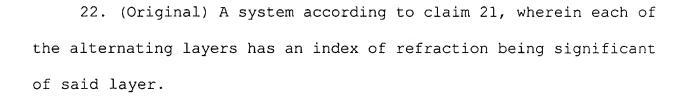
output light beam being within +/- 5 % of the average power of the transmitted/reflected secondary output light beam in the predetermined wavelength range.

14. (Original) A system according to claim 1, wherein the output power of the primary output light beam is kept within +/-20% of a predetermined output power.



- 15. (Currently Amended) A system according to claim 1, wherein the output power of the primary output light beam is kept within +/-10 % of [[the]] a predetermined output power.
- 16. (Original) A system according to claim 1, wherein the transmittance and/or reflection spectra of the dielectric coating of the beamsplitter is/are substantially invariant to temperature changes of the dielectric coating.
- 17. (Original) A system according to claim 1, wherein the substantially fixed percentage is less than 0.5%.
- 18. (Original) A system according to claim 1, wherein the substantially fixed percentage is less than 0.1%.

- 19. (Original) A system according to claim 1, wherein the light source comprises a solid state laser light source.
- 20. (Original) A system according to claim 1, wherein the light source comprises a wavelength tuneable laser light source.
- 21. (Original) A system according to claim 1, wherein the dielectric coating comprises a number of alternating layers having different indices of refraction.



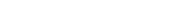
- 23. (Original) A system according to claim 21, wherein the indices of refraction of the alternating layers being within a range from approximately 1.2 to approximately 2.5.
- 24. (Original) A system according to claim 21, wherein the dielectric coating comprises at least a first layer having an index of refraction being within a range from approximately 1.2 to approximately 1.6, and at least a second layer having an index of

refraction being within a range from approximately 2.0 to approximately 2.5.

- 25. (Original) A system according to claim 1, wherein the dielectric coating comprises alternating layers of titanium-dioxide  $(TiO_2)$  and quartz  $(SiO_2)$ .
- 26. (Original) A system according to claim 1, wherein the water content of the dielectric coating is minimized.
- 27. (Original) A method of controlling the output of an optical system, the method comprising the steps of:
- emitting, by means of a light source, a first light beam being incident upon a beamsplitter having a dielectric coating,
- reflecting/transmitting a primary output light beam by means of said beamsplitter in response to the first light beam being incident thereupon,
- transmitting/reflecting a secondary output light beam by means of said beamsplitter in response to the first light beam being incident thereupon, and in such a way that the power of the secondary output light beam is a substantially fixed percentage of the power of the primary output light beam,
  - measuring the power of the secondary output light beam,



- providing, on the basis of the measured power, a control signal to the light source, and
- adjusting parameters of the first light source so that the first light beam is emitted in such a way that the output power of the primary output light beam is kept substantially constant.
- 28. (Original) A method according to claim 27, wherein the substantially fixed percentage is substantially invariant to wavelength variations of the first light beam within a predetermined wavelength range.
- 29. (Original) A method according to claim 27, wherein the transmittance and/or reflection spectra of the dielectric coating of the beamsplitter is/are substantially invariant to wavelength changes of the first light beam within a predetermined wavelength range.
- 30. (Original) A method according to claim 28, wherein the predetermined wavelength range is between approximately 780 nm and approximately 830 nm.
- 31. (Original) A method according to claim 27, wherein the beamsplitter, for an incident light beam having a wavelength within



a predetermined wavelength range, is adapted to induce a variation in the power of the transmitted/reflected secondary light beam being within +/-10 % of the power of the transmitted/reflected secondary light beam at a given wavelength within the predetermined wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/-10% of the substantially fixed percentage at the given wavelength.



32. (Original) A method according to claim 27, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, is adapted to induce a variation in the power of the transmitted/reflected secondary light beam +/-10% average being within of the of power the transmitted/reflected secondary light beam in the given wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/-10% of the average power of the transmitted/reflected secondary output light beam in the predetermined wavelength range.

33. (Original) A method according to claim 27, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, is adapted to induce a variation in the power of the transmitted/reflected secondary light beam

being within +/-5% of the power of the transmitted/reflected secondary light beam at a given wavelength within the predetermined wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/-5% of the substantially fixed percentage at the given wavelength.



34. (Original) A method according to claim 27, wherein the beamsplitter, for an incident light beam having a wavelength within a predetermined wavelength range, is adapted to induce a variation in the power of the transmitted/reflected secondary light beam within +/-5% being of the average power transmitted/reflected secondary light beam in the given wavelength range so as to provide a variation in the substantially fixed percentage of the primary output light beam being within +/- 5 % of the average power of the transmitted/reflected secondary output light beam in the predetermined wavelength range.

35. (Original) A method according to claim 27, wherein the output power of the primary output light beam is kept within +/- 20% of a predetermined output power.

- 36. (Original) A method according to claim 27, wherein the output power of the primary output light beam is kept within +/-10% of the predetermined output power.
- 37. (Original) A method according to claim 27, wherein the transmittance and/or reflection spectra of the dielectric coating of the beamsplitter is/are substantially invariant to temperature changes of the dielectric coating.
- 38. (Original) A method according to claim 27, wherein the substantially fixed percentage is equal to or less than 0.5%.
- 39. (Original) A method according to claim 27, wherein the substantially fixed percentage is equal to or less than 0.1%.
- 40. (Original) A method according to claim 27, wherein the dielectric coating comprises alternating layers of titanium-dioxide  $(TiO_2)$  and quartz  $(SiO_2)$ .
- 41. (Original) A method according to claim 27, wherein the water content of the dielectric coating is minimized.